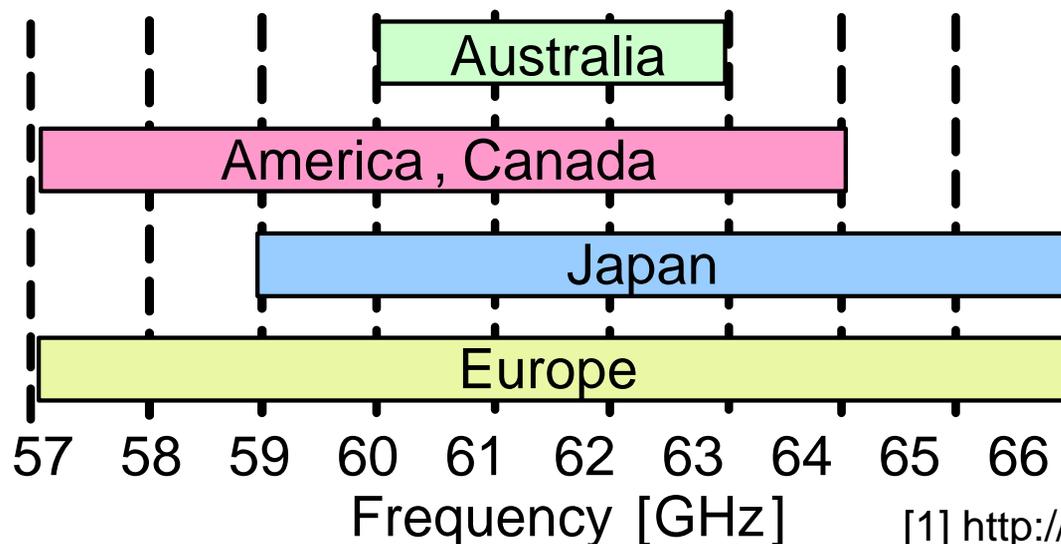


Passive Device Characterization for 60-GHz CMOS Power Amplifiers

Kenichi Okada, Kota Matsushita,
Naoki Takayama, Shogo Ito, Ning Li,
and Akira Matsuzawa

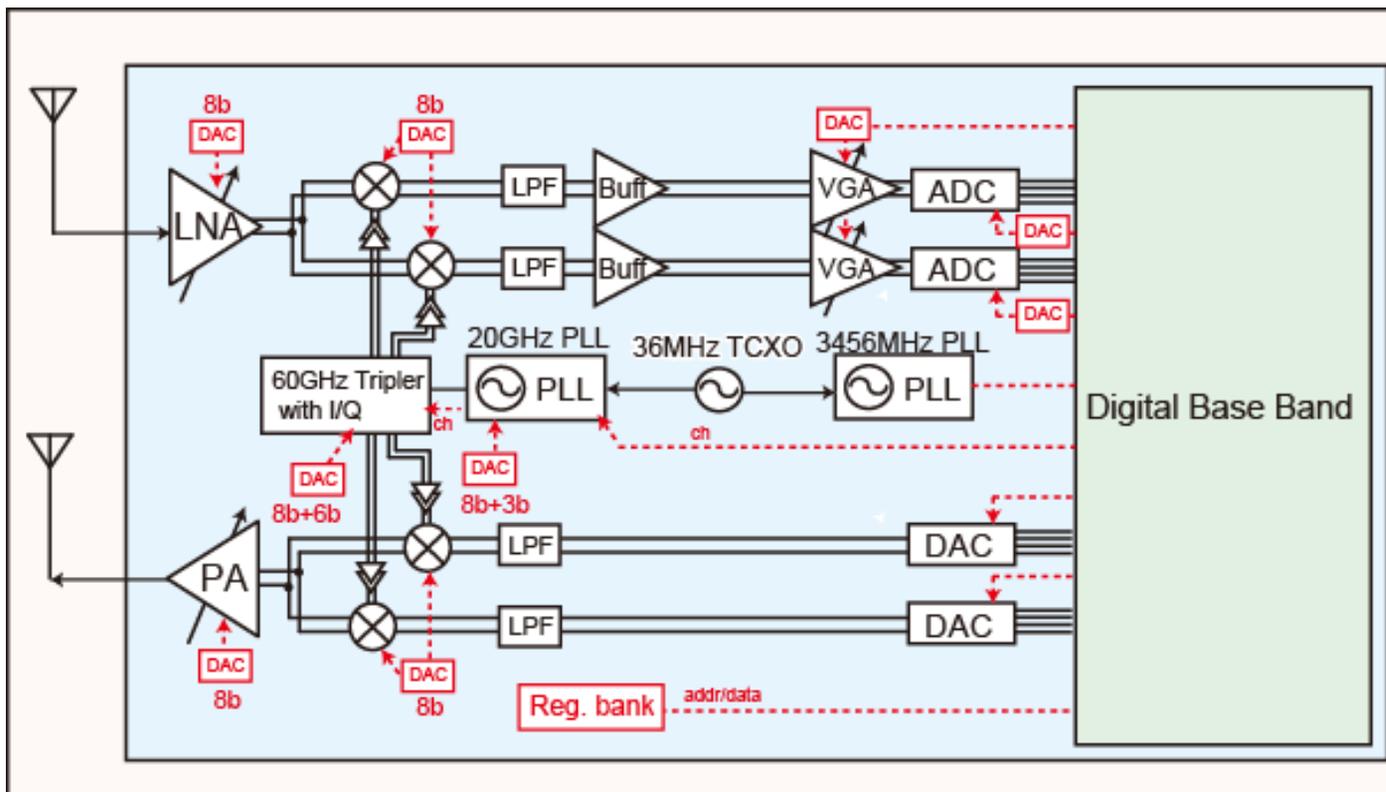
Tokyo Institute of Technology, Japan

60GHz unlicensed band



- 9GHz-BW around 60GHz
 - ➡ Several-Gbps wireless communication
- Use of CMOS process
 - ➡ Fab. cost is very important to generalize it.
RF&BB mixed chip can be realized.

Our target

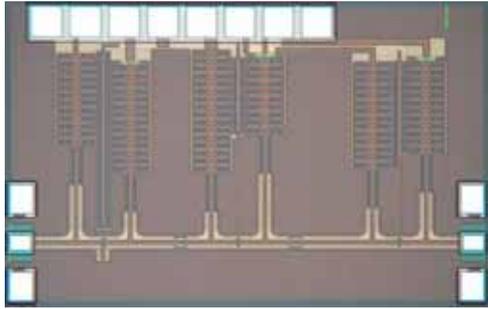


60GHz 2.16GHz-**full 4ch** direct-conversion by CMOS Tr
QPSK 3Gbps & **16QAM 6Gbps & 64QAM 9Gbps**

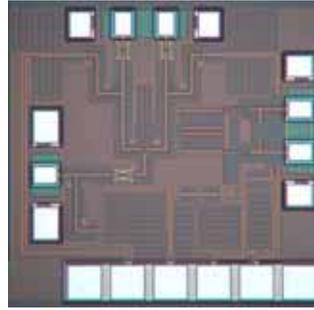
IEEE 802.15.3c conformance

Dynamic power management: <300mW for RF front-end

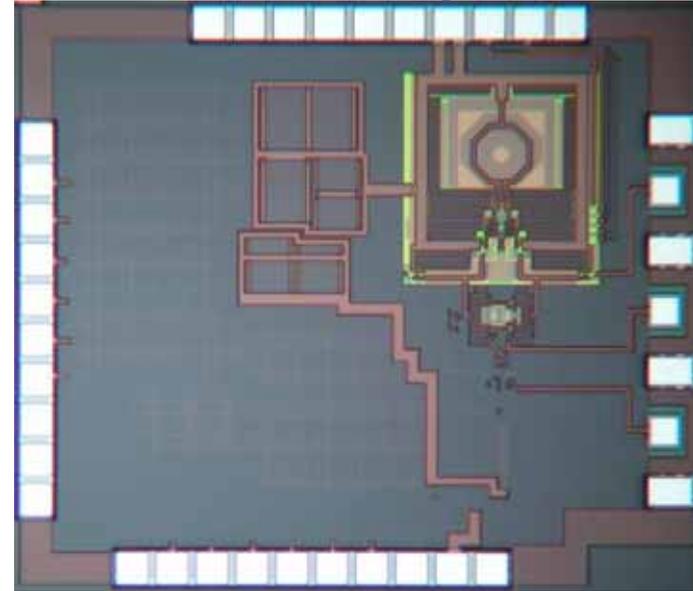
Circuit blocks of 60GHz transceiver



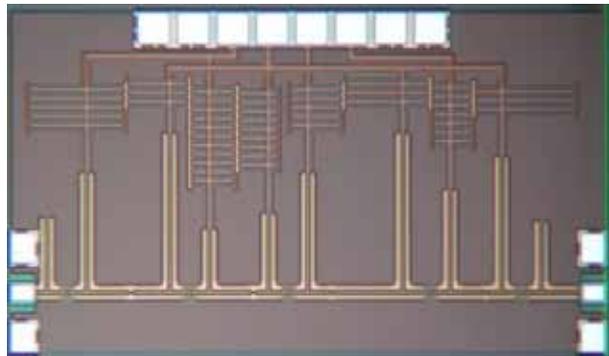
60GHz LNA



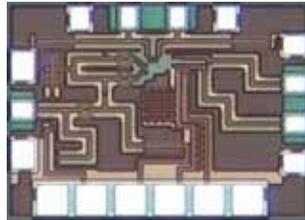
Down-Mixer



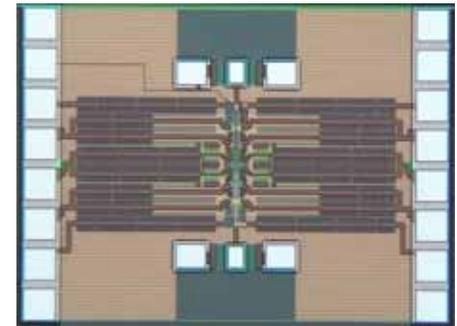
20GHz PLL



60GHz PA



Up-Mixer

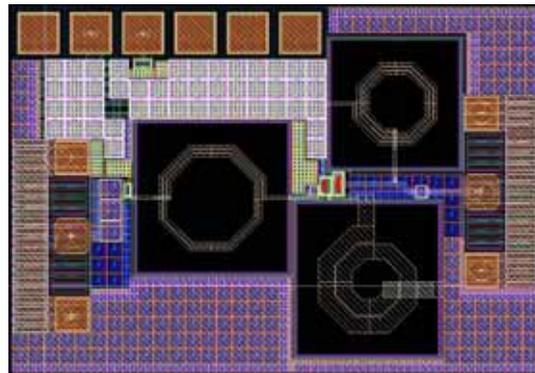


60GHz Tripler with quadrature output

Matching is very important for mmw circuit design, because

- (1) The wave length is very short,
- (2) Tr's gain is very small, and
- (3) Loss of TL is very large.

Matching blocks



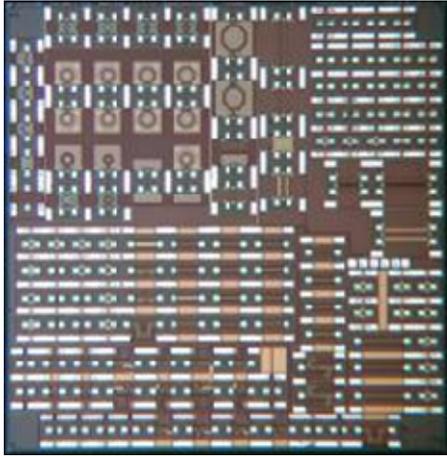
Inductor @ 5 GHz



Transmission line @ 60 GHz

At 60GHz, every interconnects should be dealt with as a distributed component.

➔ **The accurate characterization is required.**



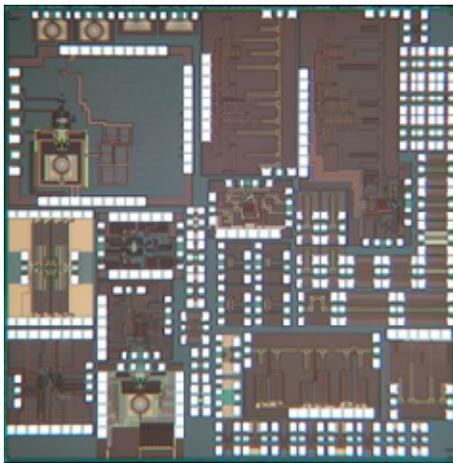
Initial T.O.

Initial T.O. for **Modeling**

- Transistors (CS, CG with various layouts)
- Transmission line (various length & Z_0)
- Branch & bend line
- Spiral inductor
- Balun
- Series capacitor
- Decoupling capacitor
- De-embedding patterns
- 1-stage amplifier for the model evaluation
- DC probe

Second T.O.

- Circuit building blocks
- Whole system

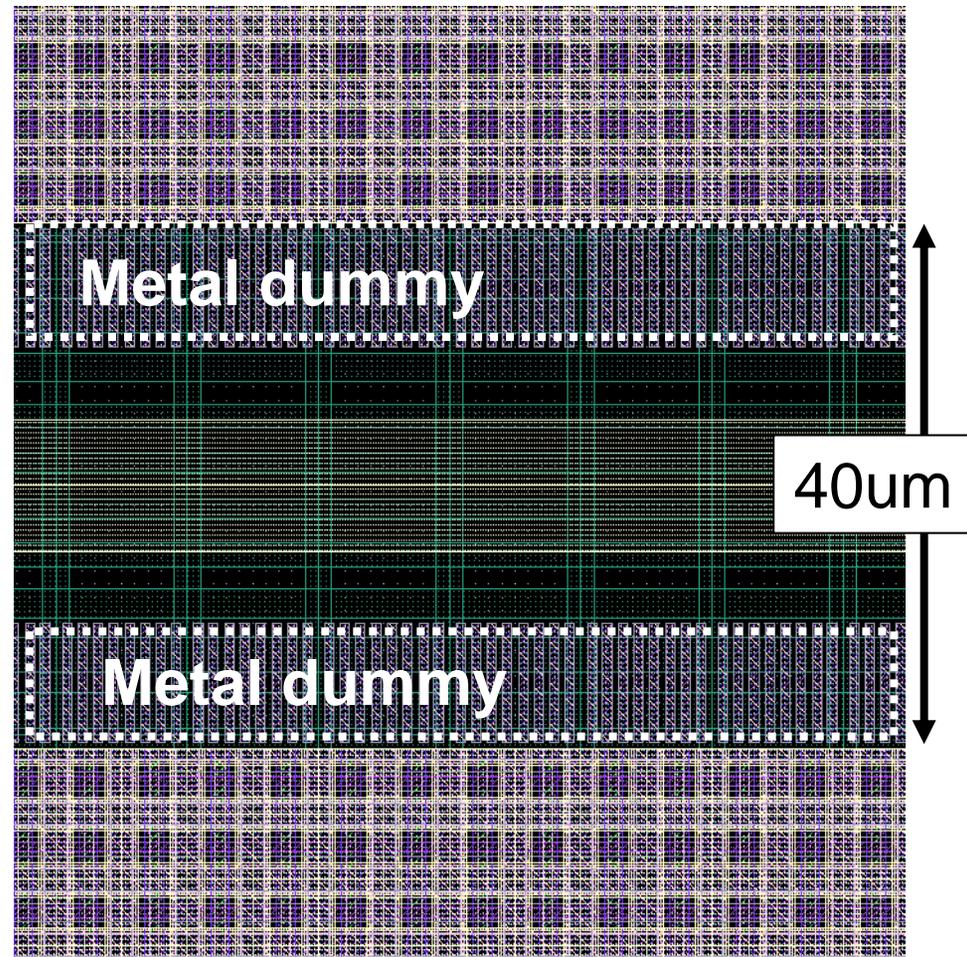
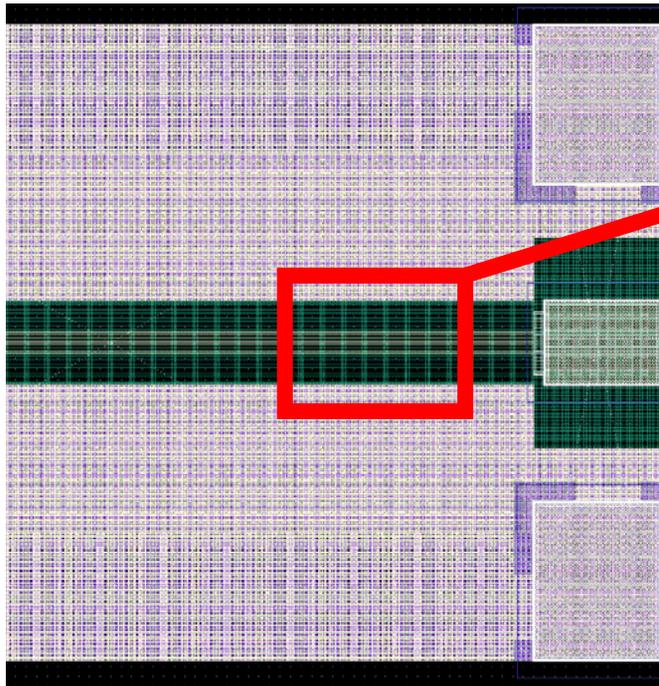


Second T.O.

- ➔ • Transmission line
- Branch & bend line
- Decoupling capacitor
- De-embedding patterns
- 1-stage amplifier
- DC probe
- 4-stage power amplifier

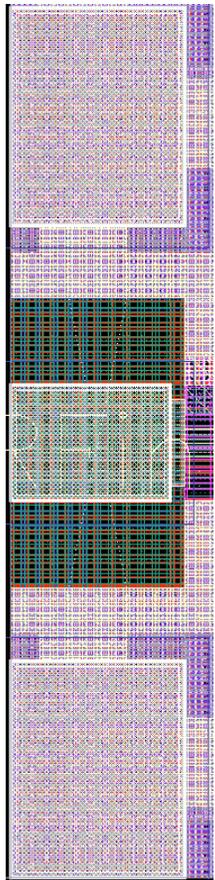
Dummy metal

To avoid random production of dummy metal, it is manually placed to keep good reproducibility.



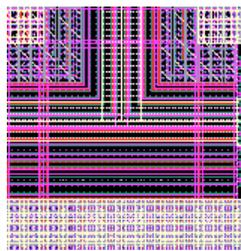
Tile-based layout

Each component is previously measured and modeled.
The same layout is utilized to maintain modeling accuracy.

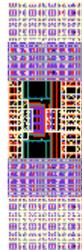


RF PAD

5 μ m pitch



T-Junction



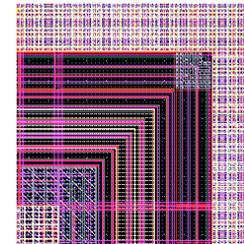
Tr



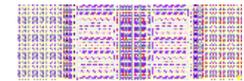
TL



C



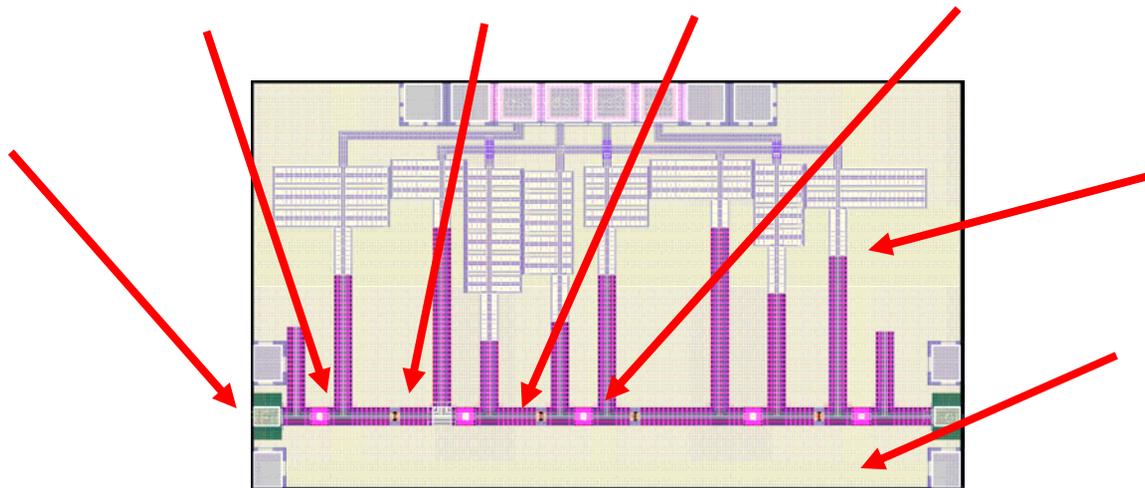
L-Bend



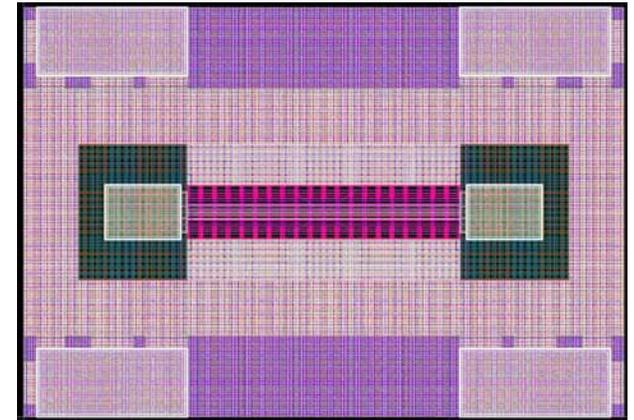
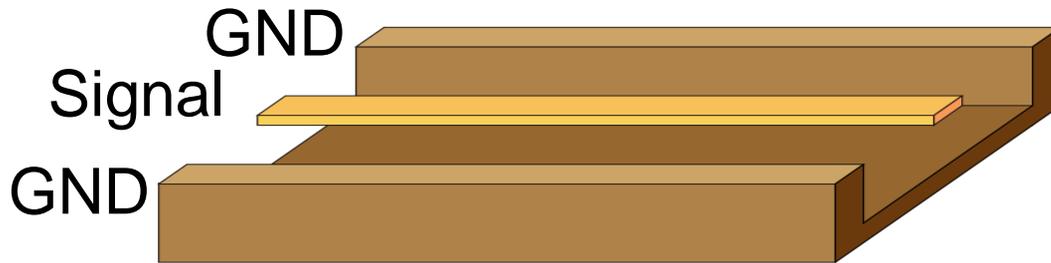
MIM TL



GND-Tile



Guided microstrip line



$$e^{-\gamma l} = \left\{ \frac{1 - S_{11}^2 + S_{21}^2}{2S_{21}} \pm K \right\}^{-1}$$

$$K = \left\{ \frac{(S_{11}^2 + S_{21}^2 + 1)^2 - (2S_{11})^2}{(2S_{21})^2} \right\}^{\frac{1}{2}}$$

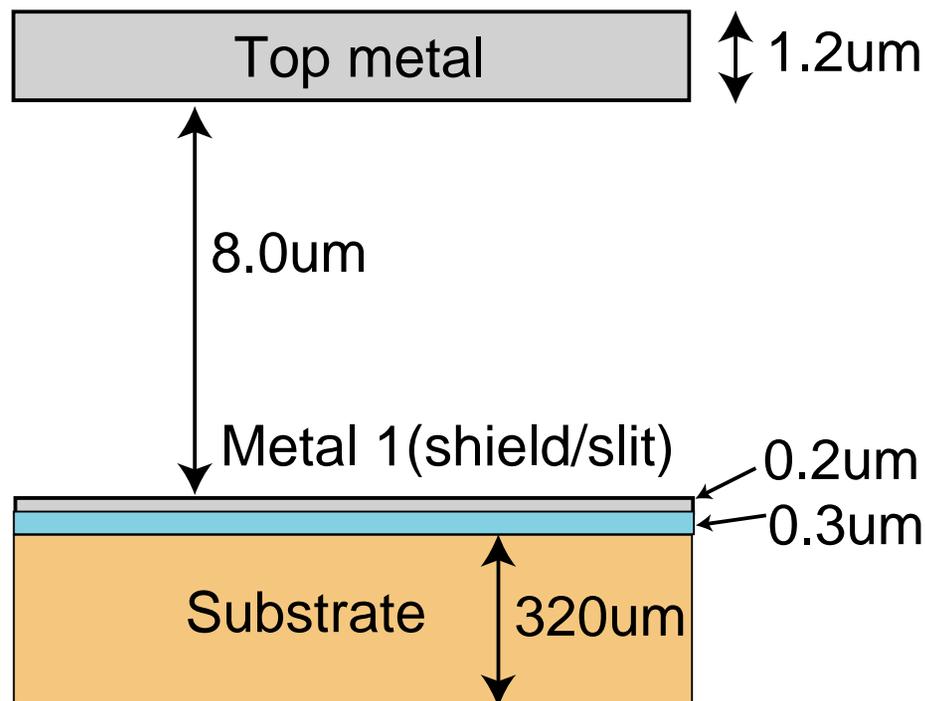
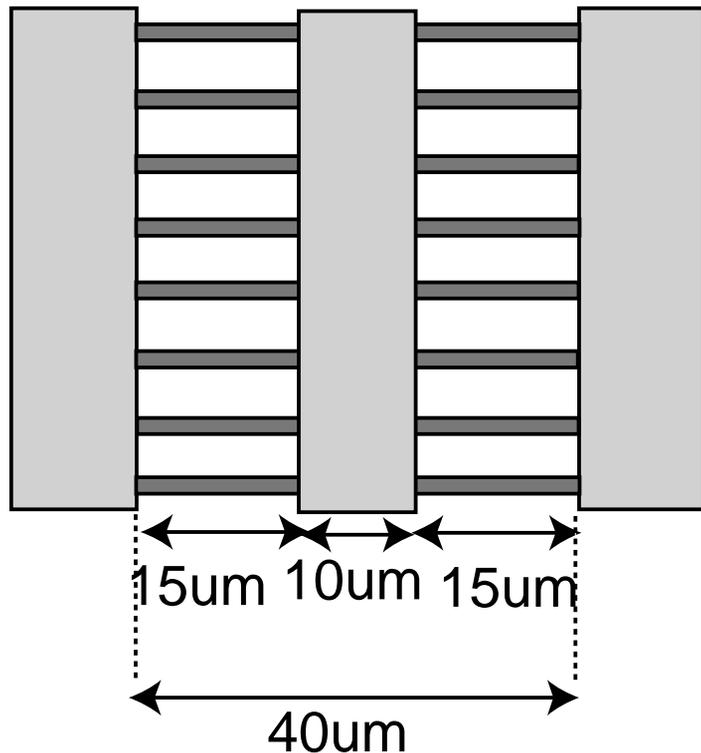
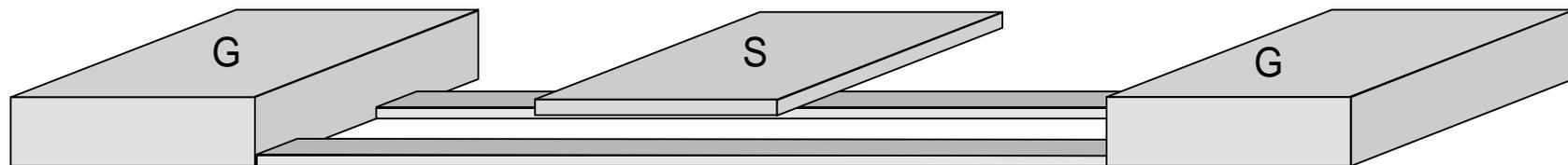
$$Z^2 = Z_0^2 \frac{(1 + S_{11})^2 - S_{21}^2}{(1 - S_{11})^2 - S_{21}^2}$$

$$\gamma = \alpha + j\beta$$

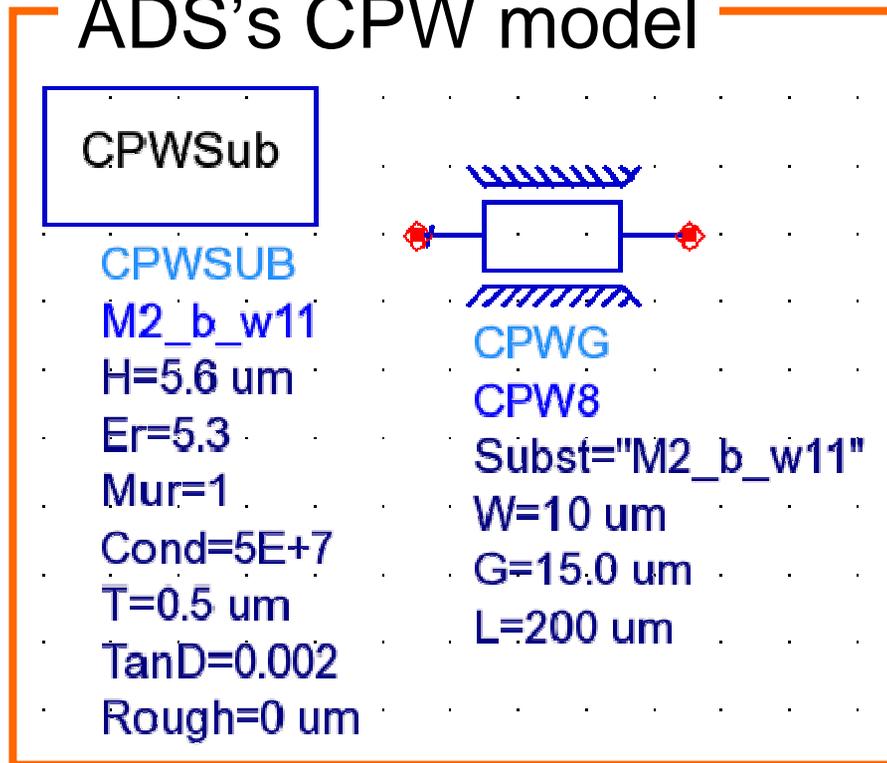
Slow-wave coplanar-waveguide is also utilized depending on a required characteristic impedance.

Cross-sectional structure

3.5Ω/mm

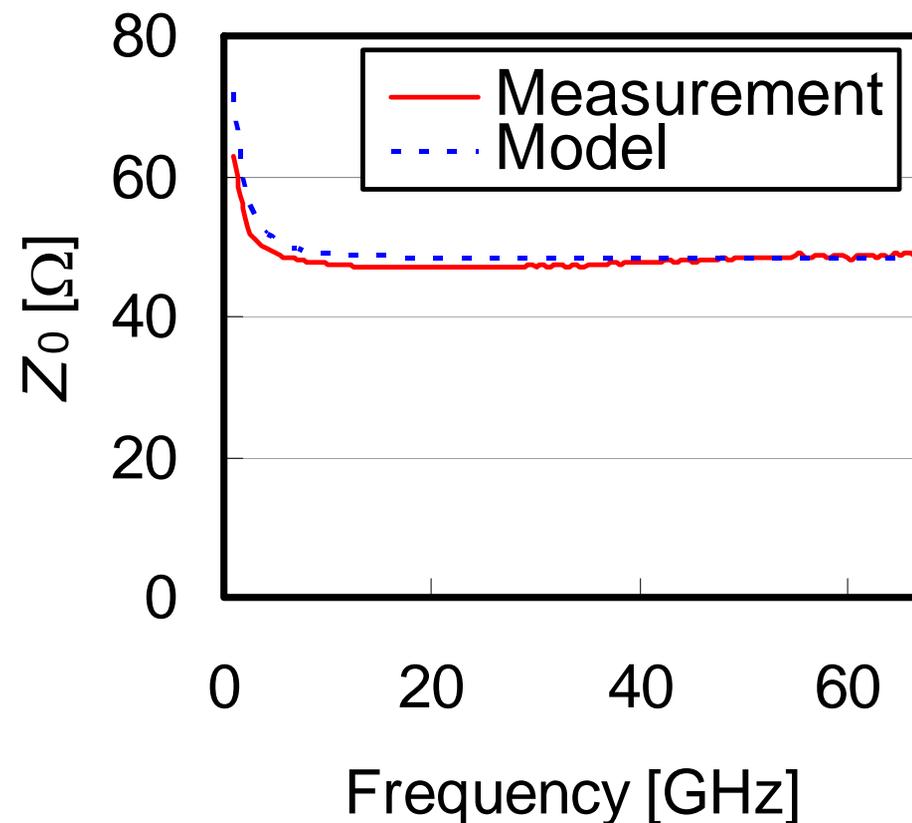
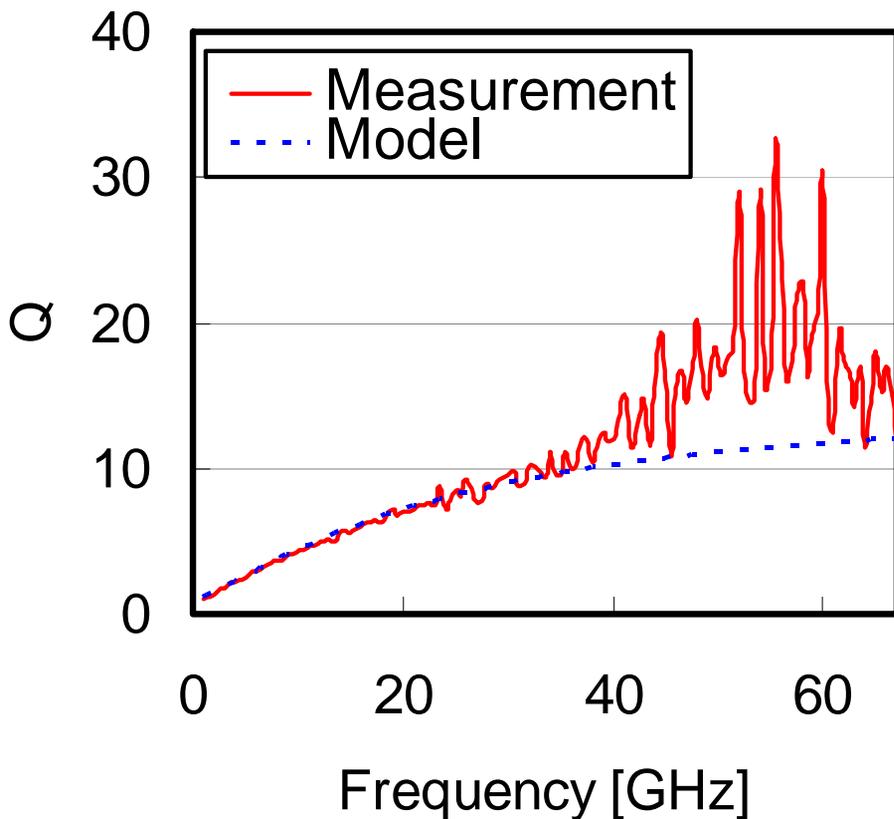


ADS's CPW model



To meet measured α , β , Q and Z_0 , substrate model is individually extracted for each structure.

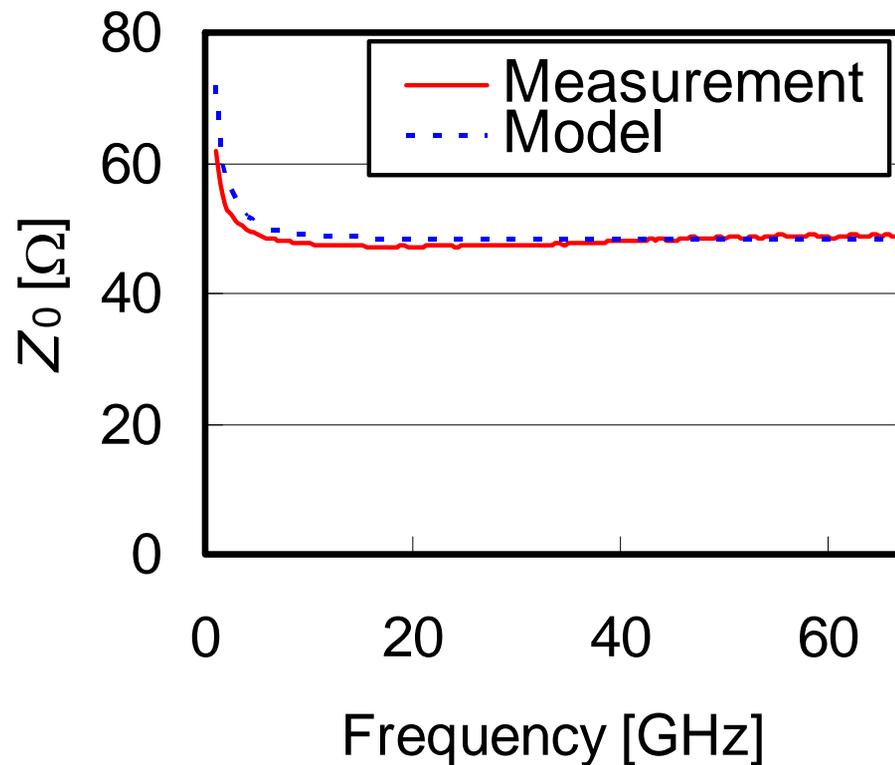
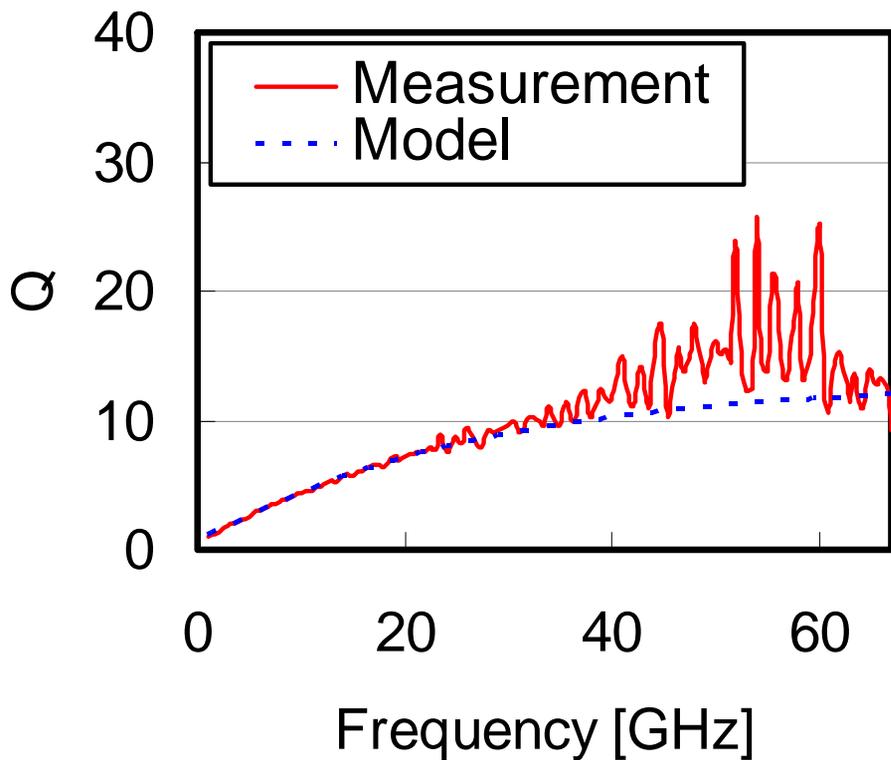
Transmission line (200 μm)



Improved Mangan's method is utilized with 200 μm and 400 μm transmission lines.

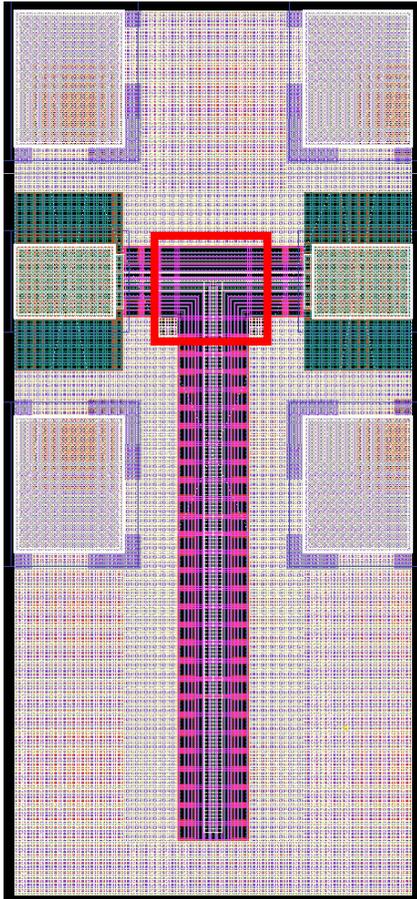
[2] A.M. Mangan, et al., IEEE Trans. on Electron Devices, vol. 53, no. 2, pp.235-241, Feb. 2006

Transmission line (400 μm)

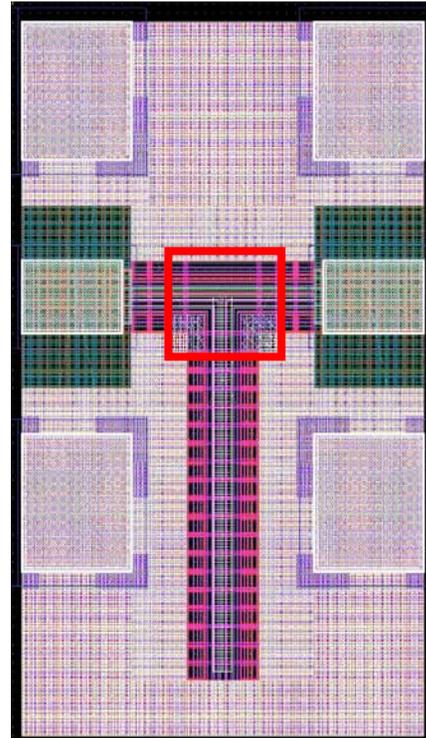


400 μm of transmission line has almost the same characteristics with that of 200 μm , which is a good proof of accurate modeling.

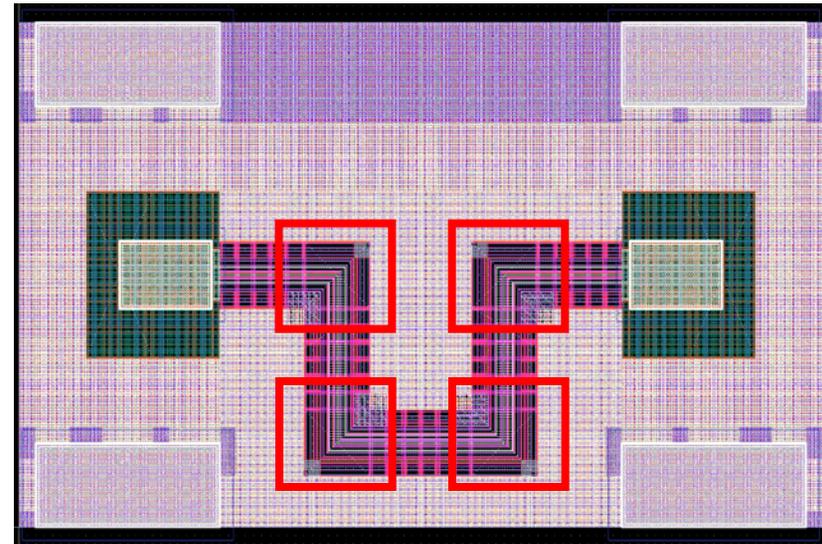
- Transmission line
- • Branch & bend line
- Decoupling capacitor
- De-embedding patterns
- 1-stage amplifier
- DC probe
- 4-stage power amplifier



with 300 μm shunt TL



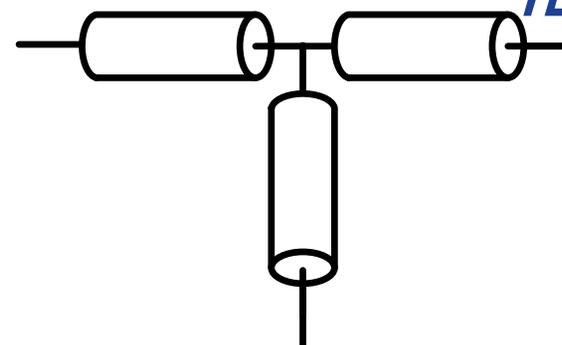
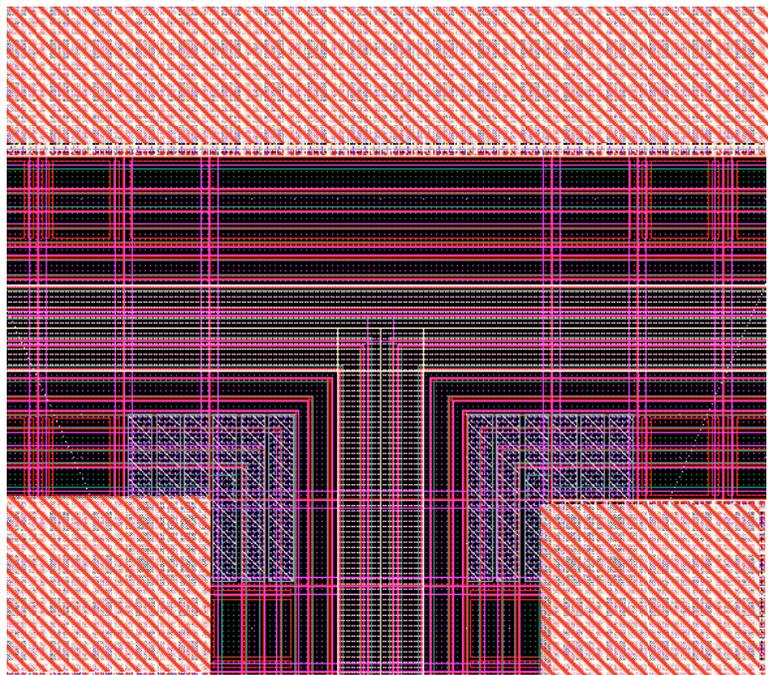
with 200 μm shunt TL



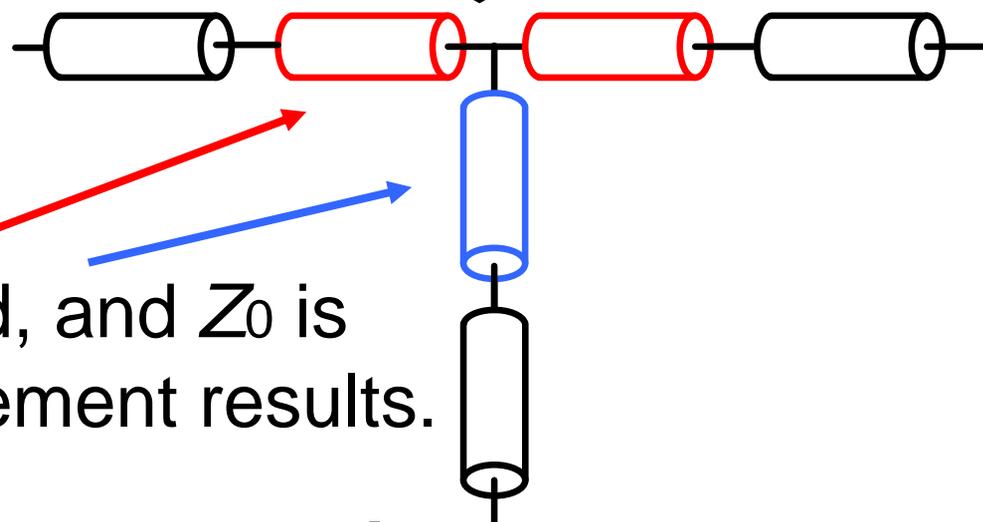
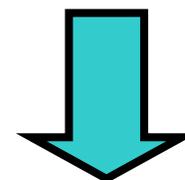
with 4 bending parts

Each red-box part is characterized as a combination of optimized transmission lines.

T-junction modeling

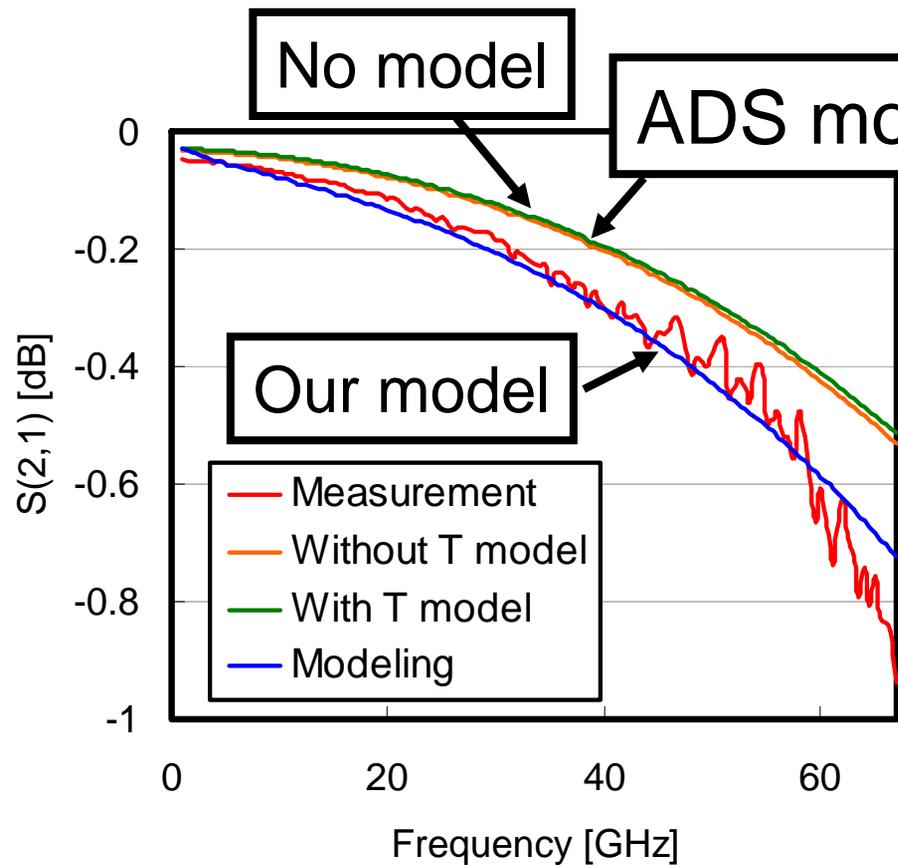


Straightforward modeling

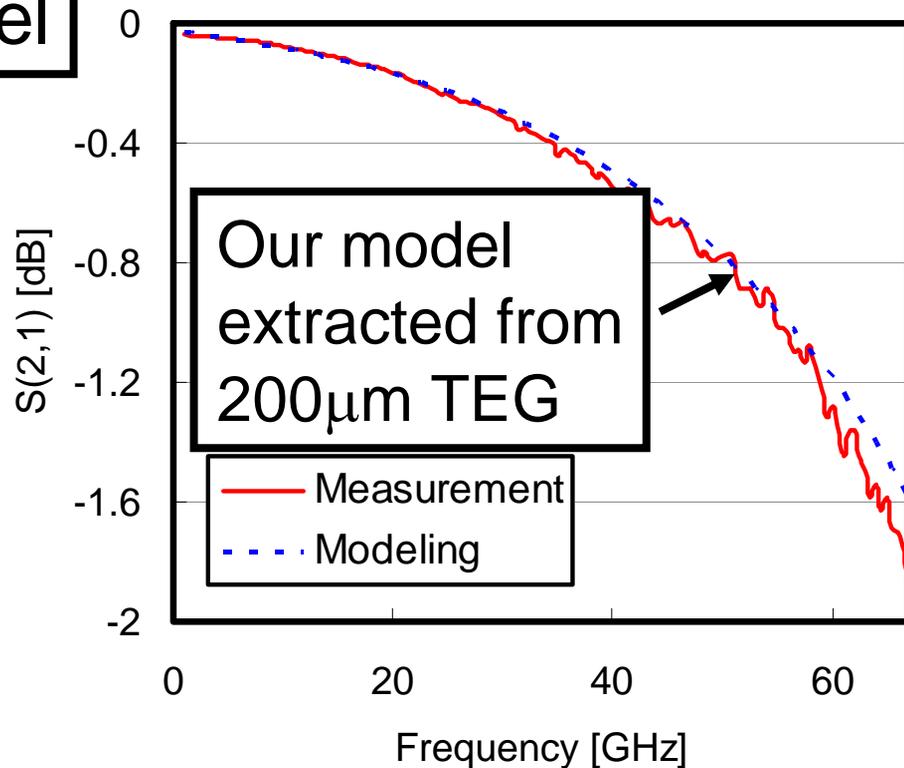


Lower Z_0 TLs are utilized, and Z_0 is adjusted for the measurement results.

Dummy metal causes unexpected response.

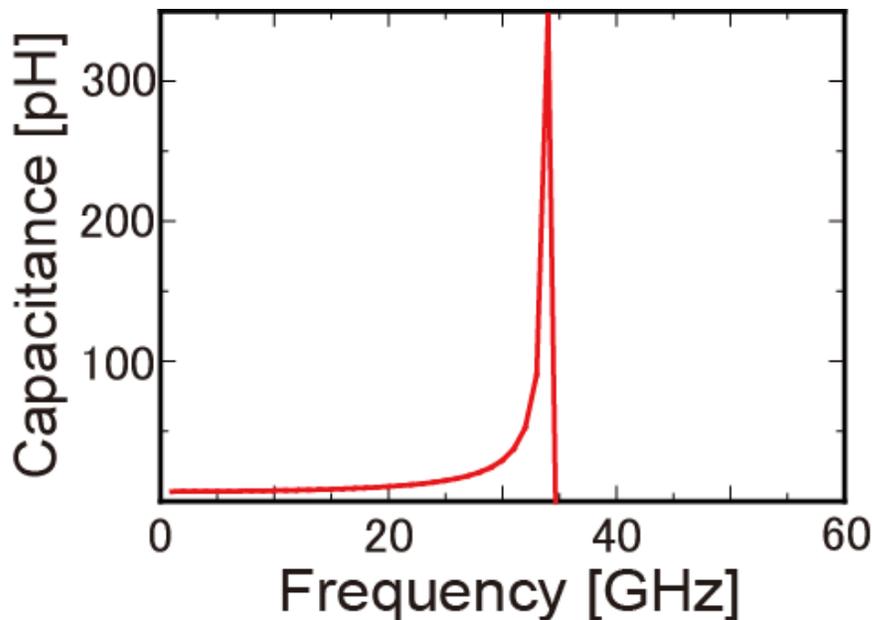
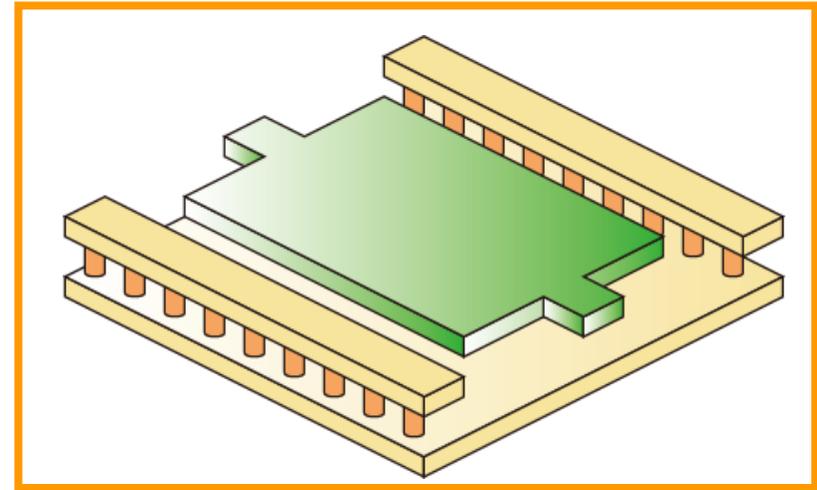
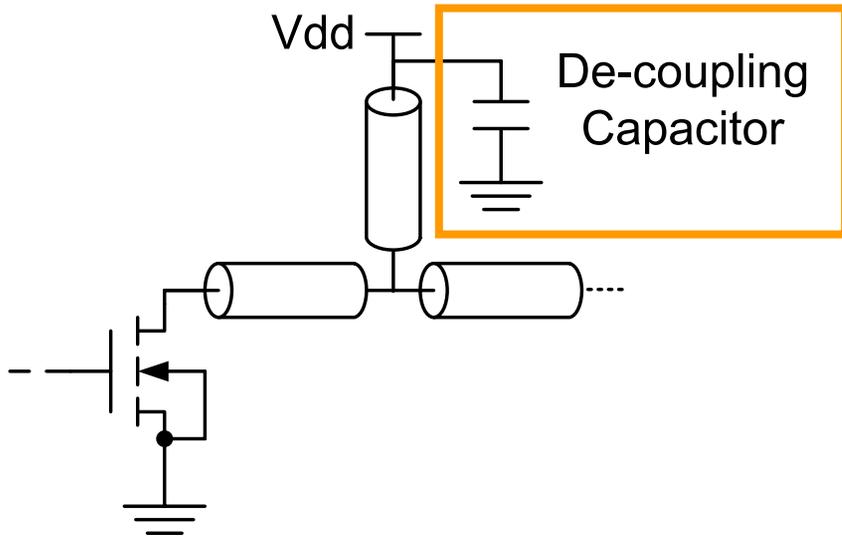


T-junction with 200 μm shunt TL

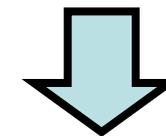


T-junction with 300 μm shunt TL

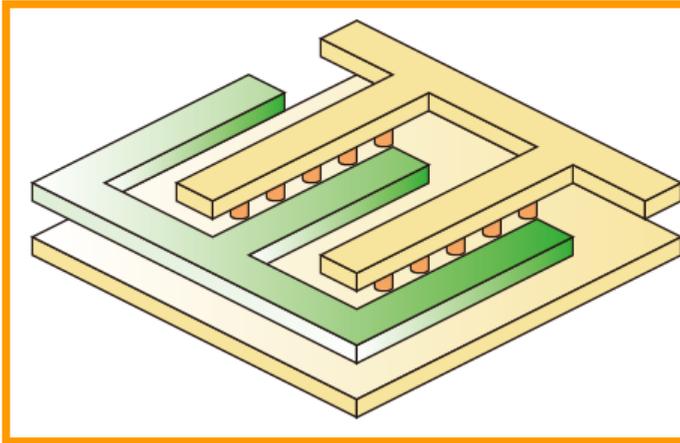
- Transmission line
- Branch & bend line
- • Decoupling capacitor
- De-embedding patterns
- 1-stage amplifier
- DC probe
- 4-stage power amplifier



Area efficiency is large, but the self-resonance freq. is low.

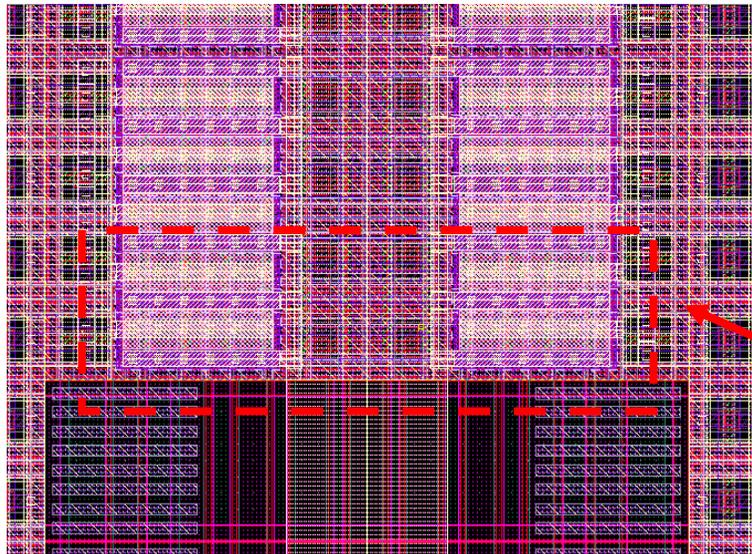


The regular layout of MIM cap. cannot be used at 60GHz.

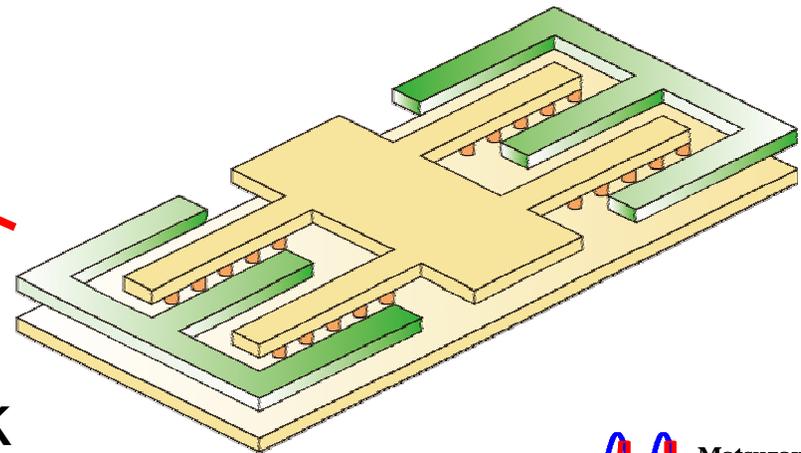


Interdigital structure with the optimized finger length is utilized.

↑ to DC-Pad

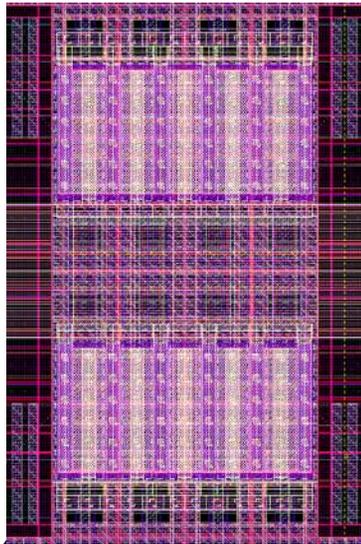
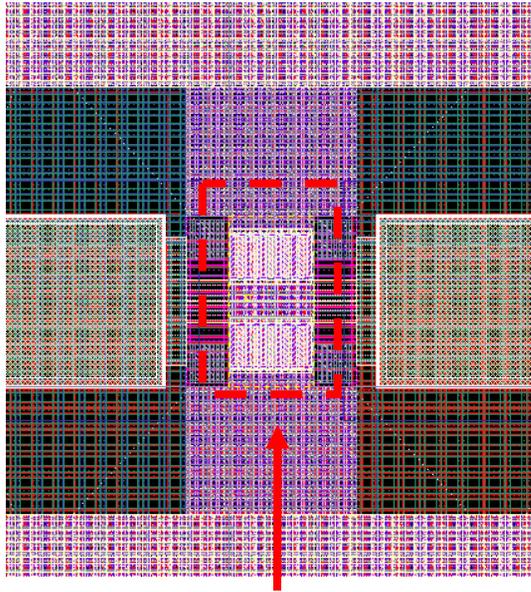


MIM cap. is modeled as a low-impedance transmission line.



↓ to Matching block

Modeled as a transmission line



TLINP

TL6

$Z=2.8 \text{ Ohm}$

$L=20 \text{ um}$

$K=205$

$A=70000$

$F=60 \text{ GHz}$

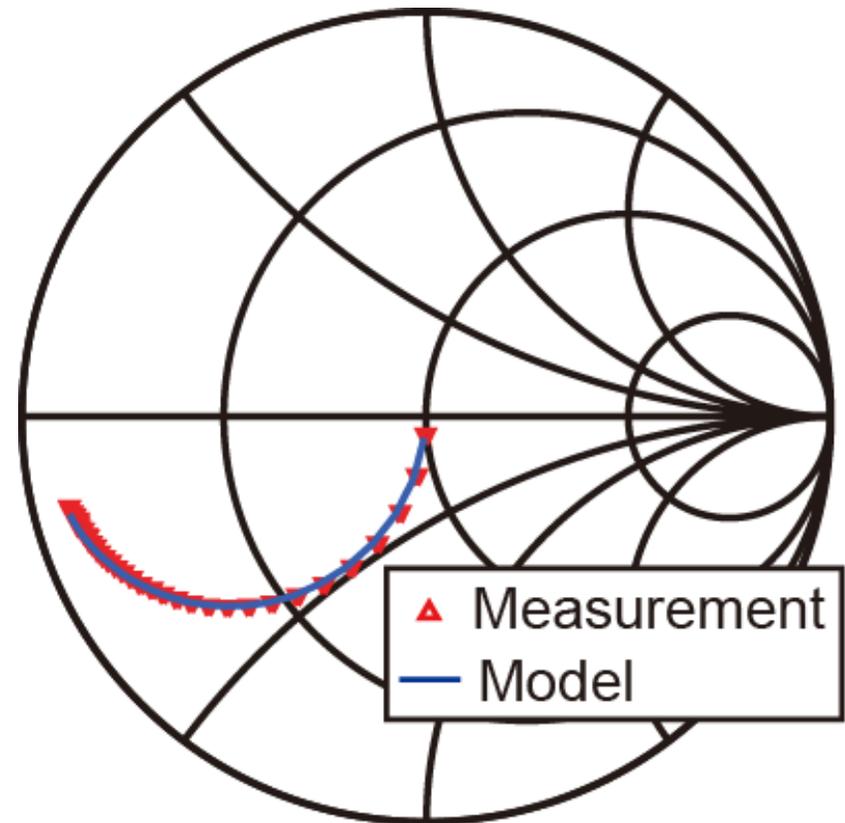
$\text{TanD}=0.02$

$\text{Mur}=1$

$\text{TanM}=1.8$

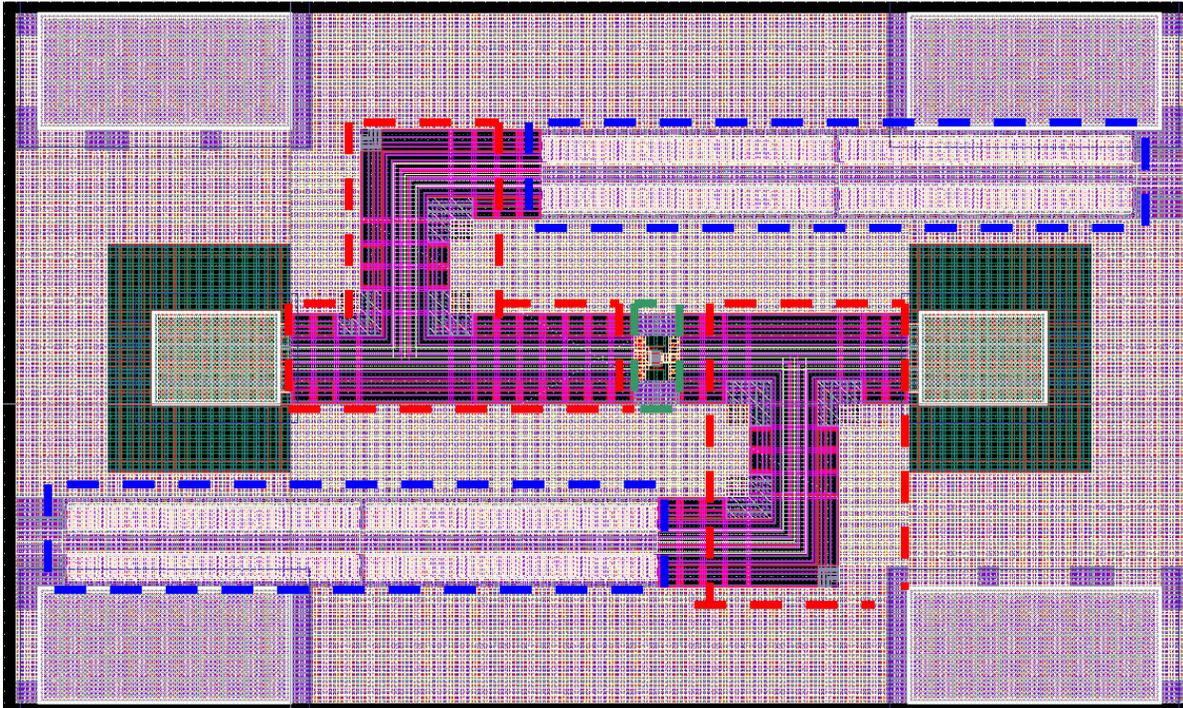
$\text{Sigma}=0$

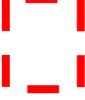
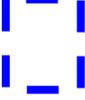
reflection 1-67GHz

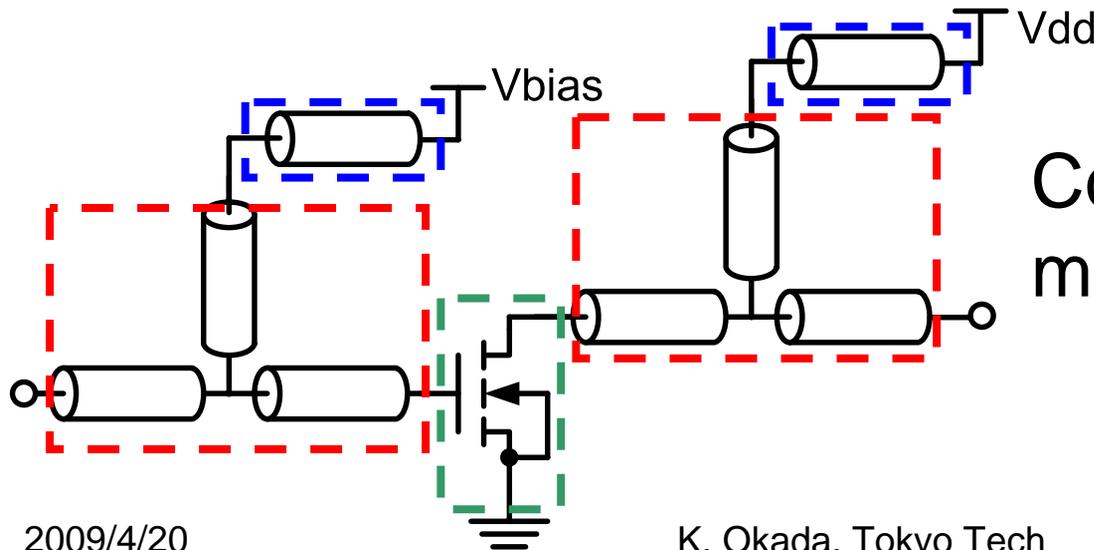


▲ Measurement
— Model

- Transmission line
- Branch & bend line
- Decoupling capacitor
- De-embedding patterns
- • 1-stage amplifier
- DC probe
- 4-stage power amplifier



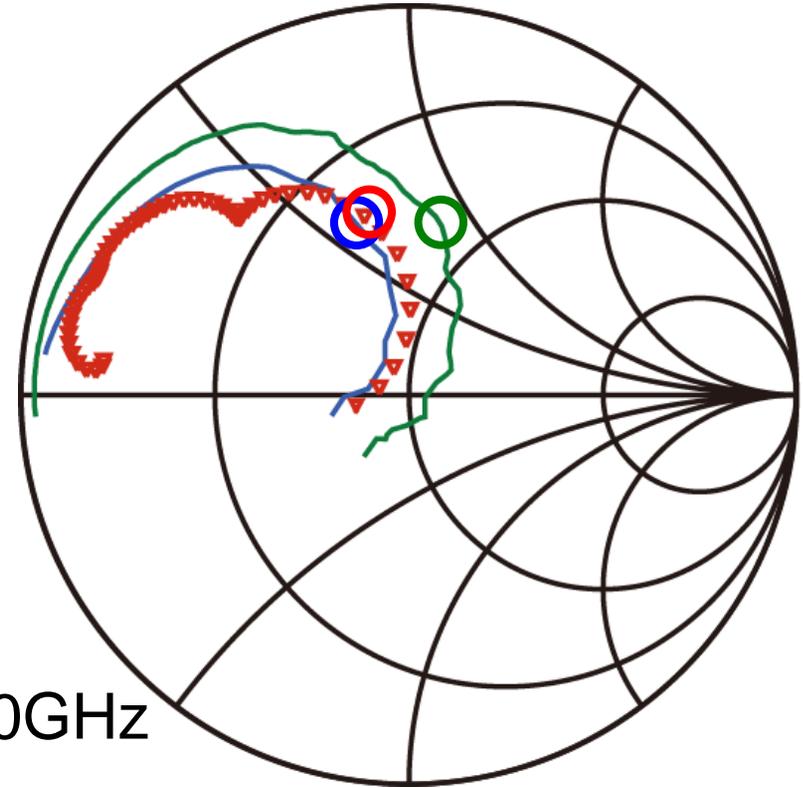
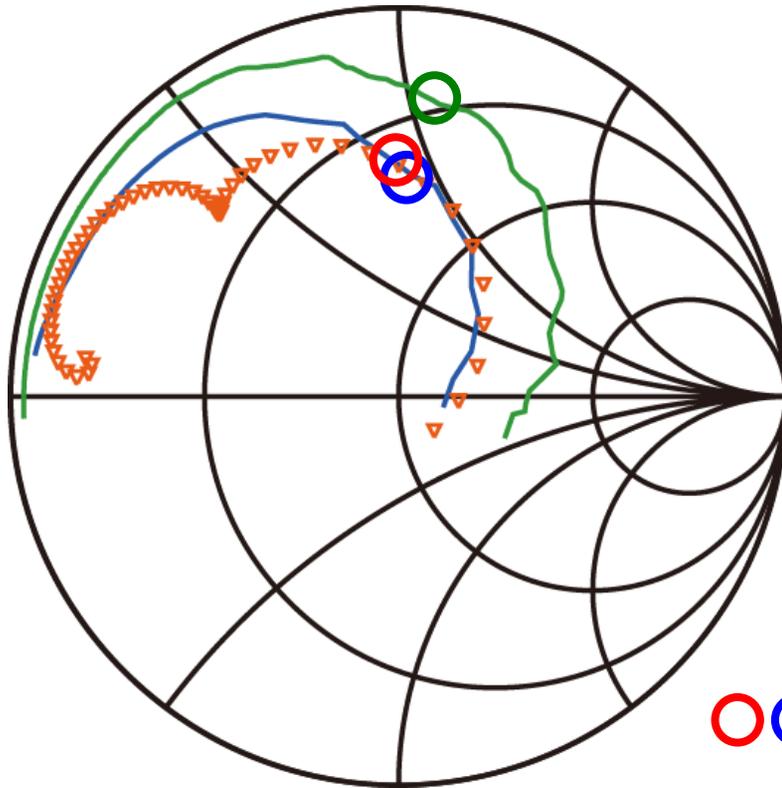
-  : Transmission line
-  : De-coupling cap.
-  : CS Transistor
(De-embedded S-parameter)



Comparison between model and measurement.

S_{11} (gate-side reflection)

S_{22} (drain-side reflection)



○ ○ ○ : 60GHz

- Measurement
- with de-coupling model
- without de-coupling model

De-coupling MIM model is required for reliable design.
90nm CMOS is used.

- De-embedding
- Transistor layout optimization
- Spiral inductor
- Balun
- RF Pad
- DC probe / bonding wire / bump / filler / PCB

See inside of top_pdk and top_meas.
top_pdk top_meas

To see simulation results, copy top_pdk.dds and top_meas.dds.

PDK

Nominal	Fast	Slow
1.5ff/um ² Min. Cap	c_min15ff	
1.0ff/um ² Min. Cap	c_min0ff	
1.2v M5 NFETs	nvh_nohv0ff	
1.2v M6 NFETs	nvh_nohv1ff	
1.2v M5 PFETs	pvh_pohv0ff	
1.2v M6 PFETs	pvh_pohv1ff	
3.3v M5 NFETs	h33m5_nohv0ff (M5)	
3.3v M6 NFETs	h33m6_nohv0ff (M6)	
Single-ended Inductors	ind_3p3_ind_0p5_stack (M4)	
Differential Inductors	inddiff_3p3_inddiff_0p5_stack (M4)	
1.2v Mosvar	mvar_12	
3.3v Mosvar	mvar33_15 (M4)	
VPRP	prp33_15 (M4)	
Unshielded resistors	rsp_rsp_pwr_rsp_0w (520-565 Ohm/Sq)	
N-Shielded resistors	rsn_rsn_pwr_rsn_0w (15 Ohm/Sq)	
P-Shielded resistors	rsp_rsp_pwr_rsp_0w (20 Ohm/Sq)	

Transistor (PDK)

Resistor (PDK)

Unshielded resistors (rsp_rsp_pwr_rsp_0w)
w=0.5um, L=3.0um
(520-565 Ohm/Sq) depending aspect ratio

N-Shielded resistors (rsn_rsn_pwr_rsn_0w)
w=0.5um, L=3.0um
(15 Ohm/Sq)

P-Shielded resistors (rsp_rsp_pwr_rsp_0w)
w=0.5um, L=3.0um
(20 Ohm/Sq)

Varactor (PDK)

1v of M5M6 w= (wrg,w) <= 103um (Design Rule)
rgr=2um, rgr=0.5um, nr=15 (Layout PDK)

1v of is recommended for VCO.

1vmin3rd, vppmin3rd
rgr=2um, rgr=0.5um, nr=15 (Layout PDK)

MIM Capacitor (PDK)

c_min0ff
1.5um <= (W) <= 103um (Design Rule)
W=5um, L=17um (Layout PDK)

c_min15ff cannot be used.

c_min is only for DC.
no resistance, no parasitic capacitance

3.3V MOS decoupling (PDK nonDFM)

3.3v_mos
W=1 <= 10um, 10um <= w <= 20um (PDK)
3.3 <= v <= 3.6
0 <= rgr <= 3.6

3.3v_mos3 3.3v_mos3_2
c_min0ff 1.0ff/um²

3.3v_mos3 can be used up to 20MHz because of large parasitic capacitance.

model C

Capacitor (model)

MIM TL (model)

Transmission Line (model)

RF PAD (model)

60um x 40um RF PAD

DC probe (meas.)

only reliable up to 20GHz

PVT

MIM TL

TL with L/T

NMOS

R

DC probe

PMOS

RF PAD

Varactor

MIM

MOS cap

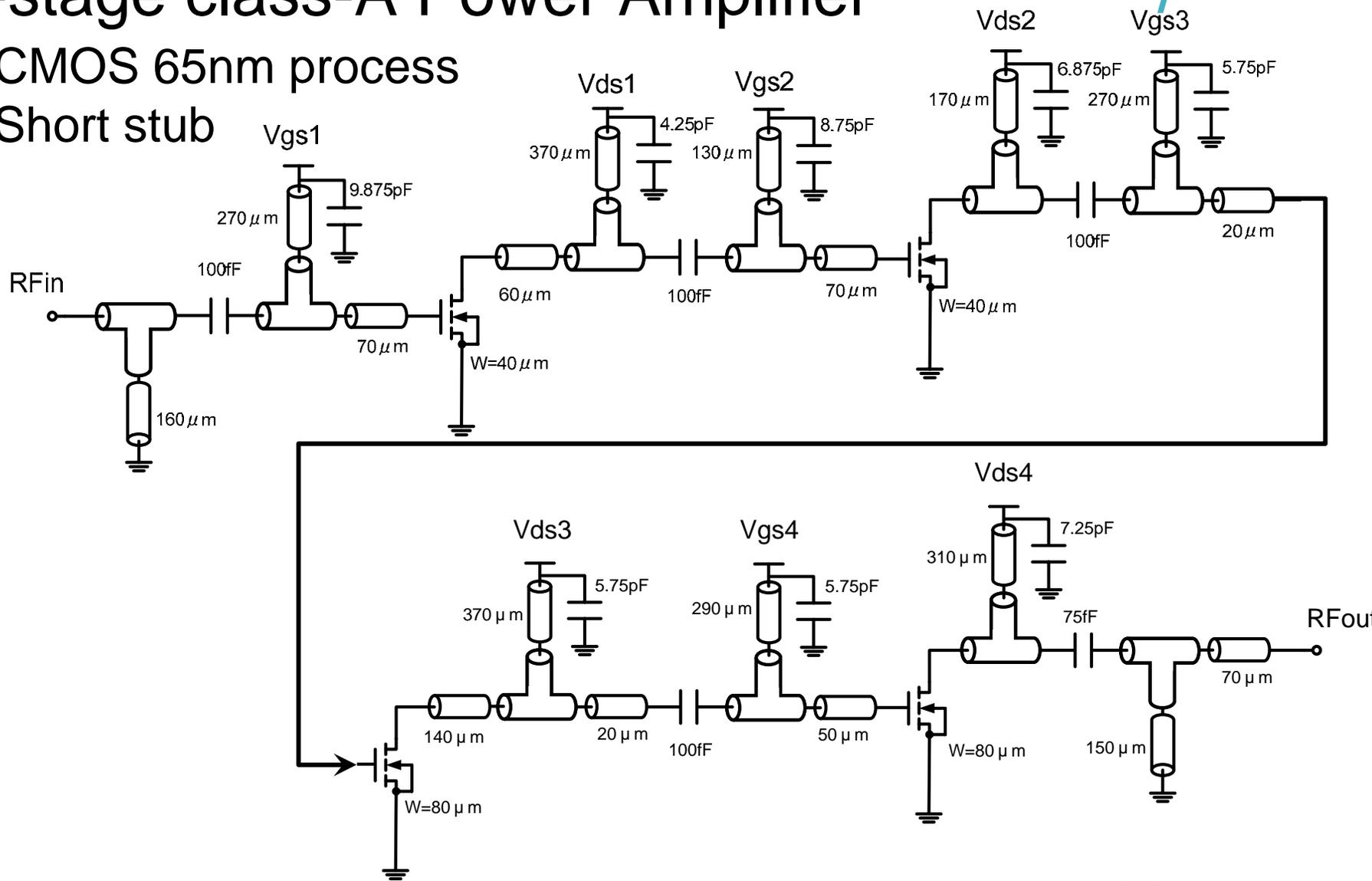
Each component is implemented as an in-house PDK for Agilent ADS.

- Transmission line
- Branch & bend line
- Decoupling capacitor
- De-embedding patterns
- 1-stage amplifier
- DC probe
- ➔ • 4-stage power amplifier

PA design

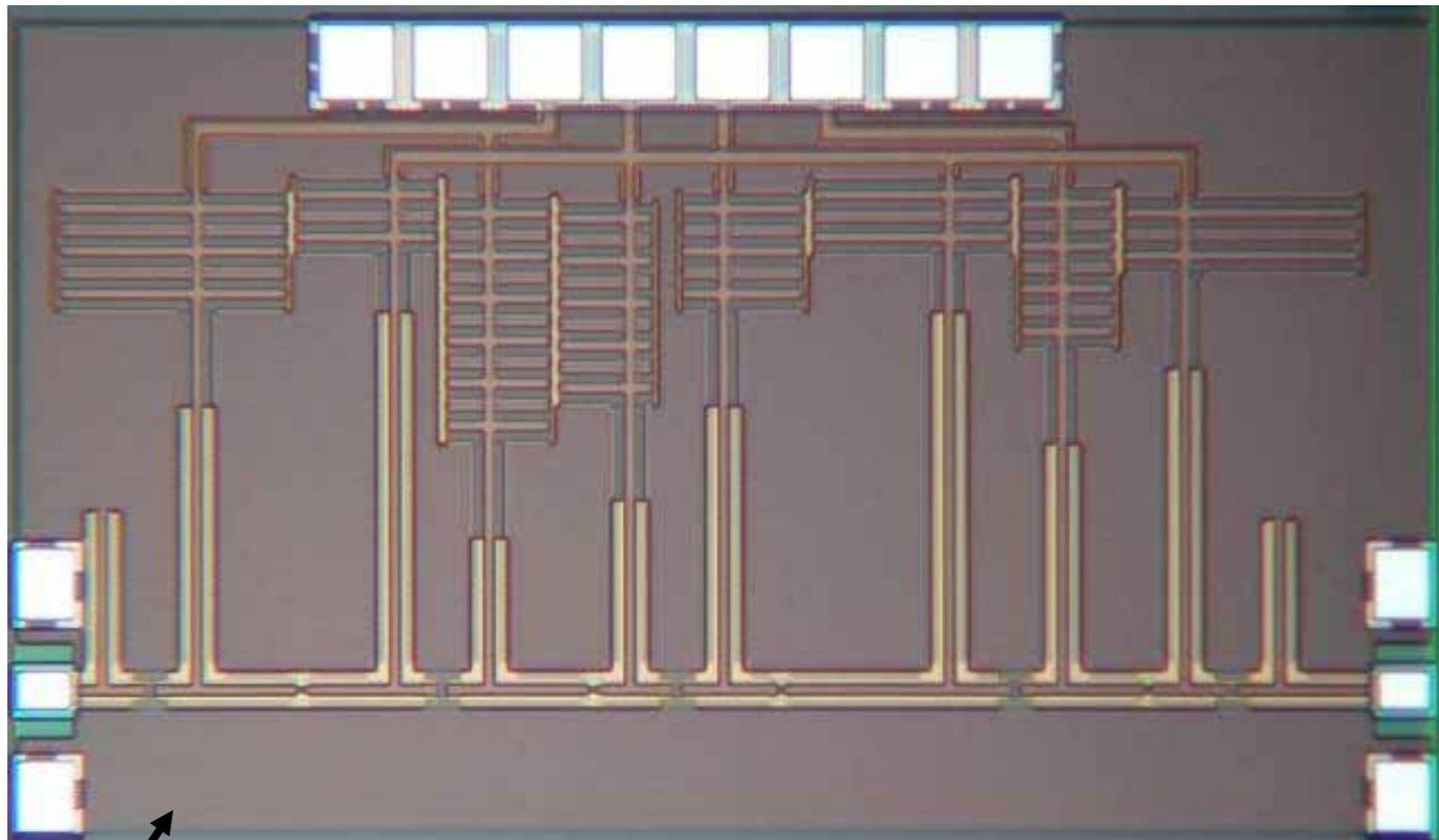
4-stage class-A Power Amplifier

- CMOS 65nm process
- Short stub



Chip micrograph

60GHz CMOS PA



0.85mm

OUT

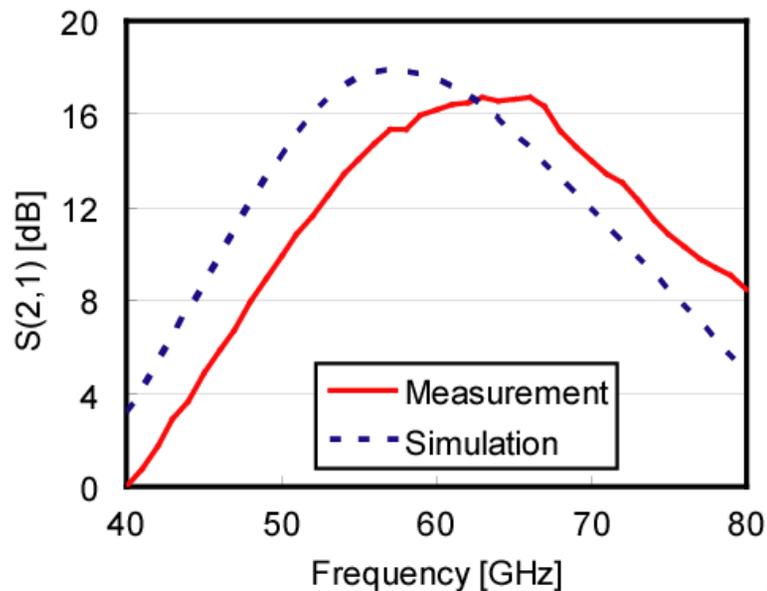
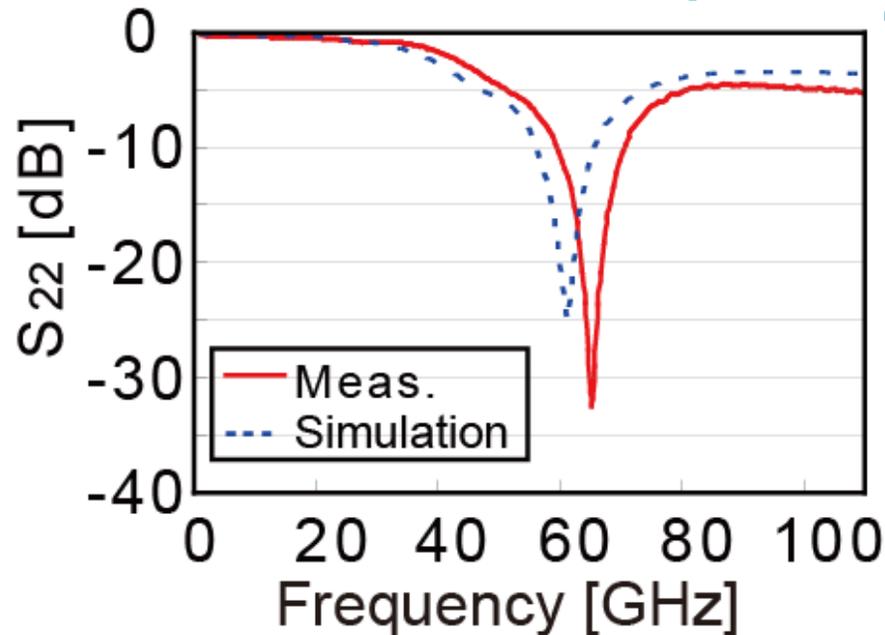
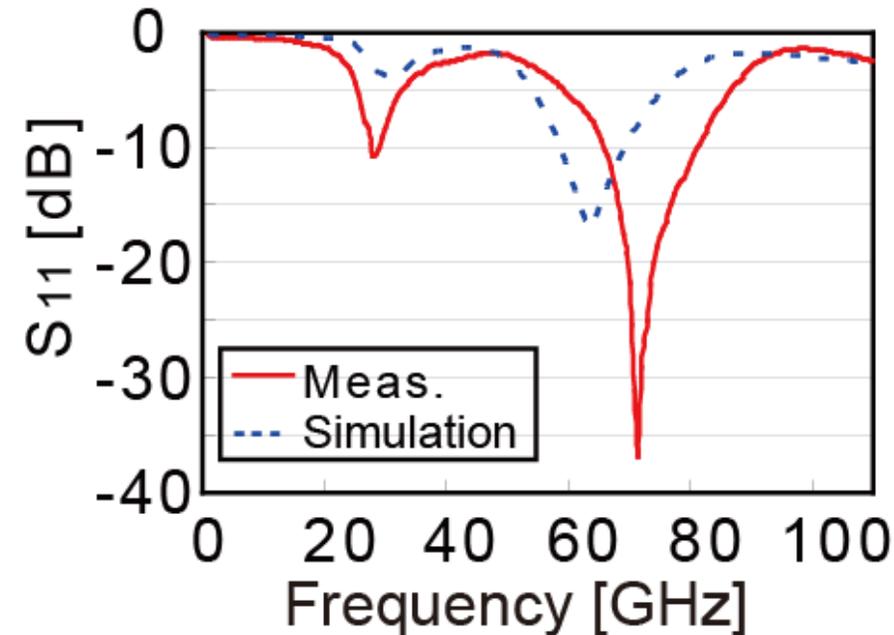
IN

1.5mm

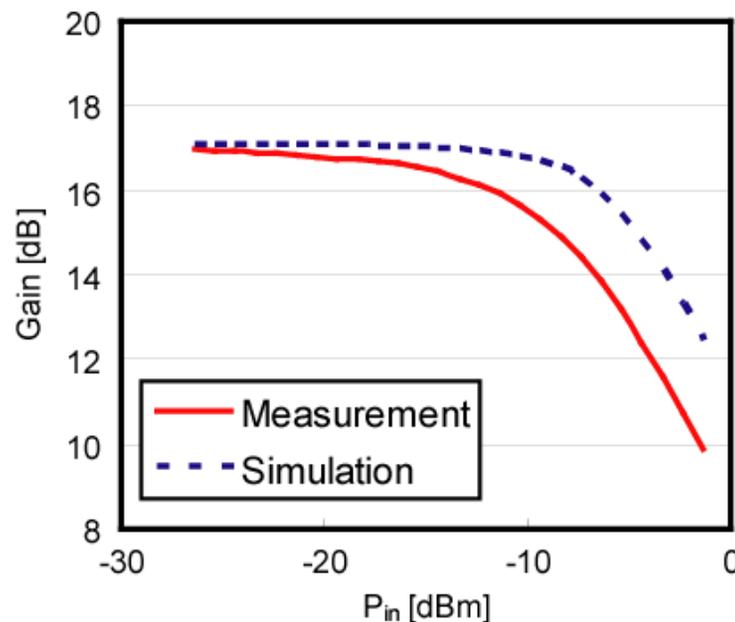
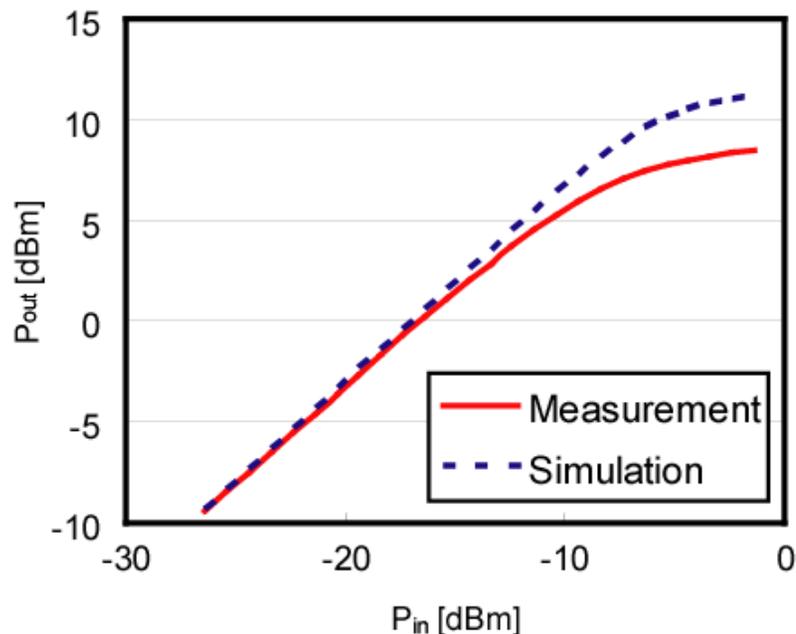
surface ground plane

CMOS 65nm process

Measurement results



@61.5GHz
 S_{21} : 16.4dB
 S_{11} : <-8dB
 S_{22} : <-10dB



Power gain: 16.4dB

P_{1dB} : 4.6dBm

P_{DC} : 122mW

Reference	Technology	Freq. [GHz]	Gain [dB]	P_{1dB} [dBm]	PAE@ P_{1dB} [%]	P_{DC} [mW]	V_{DD} [V]
[4] JSSCC 2007	90nm CMOS	61	5.2	6.4	7.4	21	1.5
[5] RFIC 2008	90nm CMOS	63	14	11	15	81	1.2
[6] ISSCC 2008	90nm CMOS	60	8.2	8.2	2.4	229	1.2
[7] ISSCC 2008	90nm CMOS	60	5.5	9	6	80	1
[8] ISSCC 2008	90nm CMOS	60	13.3	10.5	8	150	1
[9] ISSCC 2009	65nm CMOS	60	15.8	2.5	3.95	43.5	1
[10] ISSCC 2009	45nm CMOS	60	13.8	11	-	-	1.1
[11] MWCL 2009	90nm CMOS	60	30	10.3	6	178	1.8
This work	65nm CMOS	61.5	16.4	4.6	2.3	122	1.2

[4] T.Yao, *et al.*, JSSC 2007(Tronto Univ.) [5] T.L.Rocca, *et al.*, RFIC 2008 (UCLA) [6] T.Suzuki, *et al.*, ISSCC 2008 (Fujitsu)
 [7] D. Chowdhury, *et al.*, ISSCC 2008 (UCB) [8] M. Tanomura, *et al.*, ISSCC 2008 (NEC)
 [9] W.L. Chan, *et al.*, ISSCC 2009 (Delft Univ.) [10] K. Raczkowski, *et al.*, ISSCC 2009 (KU Leuven&IMEC)
 [11] J.-L.Kuo, *et al.*, MWCL 2009 (NTU)

In this presentation, I presented a modeling approach to design a 60GHz CMOS amplifiers.

1. Design issue of TL on CMOS chips is different from that of compound semiconductors.
e.g., dummy metal, lossy substrate, large conductive loss, etc
2. Branch modeling
3. Distributed modeling of de-couple MIM cap.
4. Evaluation using a 1-stage amplifier

By the proposed modeling method, 60GHz power amplifier can be successfully realized.

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